



PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

APPLICANTS: Hyun HUH et al. CONF. NO.: 2580
SERIAL NO.: 10/647,297 GROUP: 1771
FILED: August 26, 2003 EXAMINER: Hai Vo
FOR: Polishing Pad Containing Embedded Liquid Microelements and Method
of Manufacturing the Same
DOCKET NO.: 47881-000003/US

Customer Service Window
Randolph Building
401 Dulany Street
Alexandria, VA 22314
Mail Stop Amendment

February 10, 2006

RESPONSE TO RESTRICTION REQUIREMENT

Dear Sir:

Responsive to the Examiner's Restriction Requirement dated December 12, 2005, the period for response having been extended one (1) month to February 12, 2006, the following remarks are respectfully submitted in connection with the above-referenced application.

REMARKS

Claims 1-16 remain in the present application.

Election/Restriction Requirement

The Examiner has imposed a Restriction Requirement, and requested that Applicants elect one of two identified groups of claims for prosecution in connection with the present application. The two groups of claims are as follows: